

UNITED STATES PATENT AND TRADEMARK OFFICE
CERTIFICATE OF CORRECTION

PATENT NO. : 6,949,744 B2
DATED : September 27, 2005
INVENTOR(S) : Michael Steigerwald et al.

Page 1 of 1

It is certified that error appears in the above-identified patent and that said Letters Patent is hereby corrected as shown below:

Column 12,

Line 41, "**17b₁, 17d₂ and 17d₃, ...**" should read -- **17d₁, 17d₂ and 17d₃, ...** --;

Line 53, "..., the electron microscopy system id does not ..." should read -- ..., the electron microscopy system **1d** does not ... --;

Column 14,

Line 9, "An electron microscopy system if schematically shown in ..." should read -- An electron microscopy system **1f** schematically shown in ... --;

Column 16,

Line 23, "...time to is depicted." should read -- time **t₀** is depicted. --;

Line 27, "At the time to the electrical field ..." should read -- At the time **t₀** the electrical field ... --;

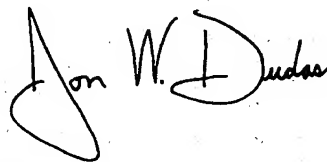
Column 24,

Line 1, "... detecting a time structure of electron intensifies of ..." should read -- ... detecting a time structure of electron intensities of ... --; and

Line 11, "... tion of the secondary caused by the deflecting electro-..." should read -- tion of the secondary electrons caused by the deflecting electro- ... --.

Signed and Sealed this

Twentieth Day of December, 2005



JON W. DUDAS

Director of the United States Patent and Trademark Office